

Integrated Device Technology, Inc. 6024 Silver Creek Valley Road, San Jose, CA - 95138

# PRODUCT/PROCESS CHANGE NOTICE (PCN)

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PCN #: <b>A1508-0</b>	<b>3</b> I	DATE: 11-Sep-2015	MEANS OF DISTI	NGUISHING CHA	NGED DEVICES:
Product Affected: Refer to A	6.0mm x 6.0mm VFQI ttachment II for the affe		<ul><li>□ Product Mark</li><li>■ Back Mark</li><li>□ Date Code</li><li>□ Other</li></ul>	Lot # will have: "RC" prefix for A	ASECL, Taiwan
Date Effective: 1	1-Dec-2015				
Contact: ID	T PCN DESK		Attachment:	Yes	☐ No
E-mail: pc	ndesk@idt.com		Samples: Please co		les representative for
DESCRIPTION AN	D PURPOSE OF CHA	ANGE:			
<ul> <li>□ Die Technology</li> <li>□ Wafer Fabrication</li> <li>□ Assembly Process</li> <li>□ Equipment</li> <li>□ Material</li> <li>□ Testing</li> <li>■ Manufacturing Sit</li> <li>□ Data Sheet</li> <li>□ Other</li> </ul>	i Trocess	This notification is to alternate Assembly fac There is no change to Attachment I details the Attachment II shows the	cility. the moisture performa ne qualification data fo	nce.	ASECL, Taiwan as the
	ALIFICATION SUM n data shown in Attachr				
CUSTOMER ACK	NOWLEDGMENT OF	F RECEIPT:			
to grant approval or it will be assumed th	that you require written request additional infor at this change is accept that to ship either version in has been depleted.	mation. If IDT does no able.	ot receive acknowledge	ement within 30 day	ys of this notice
Customer:			Approval for	shipments prior	r to effective date.
Name/Date:		I	E-Mail Address:		
Title:		I	Phone# /Fax# :		
CUSTOMER COM	MENTS:				
IDT ACKNOWI FI	OGMENT OF RECEI	рт			
			D. A. TITE		
RECD. BY:			DATE:		

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### PRODUCT/PROCESS CHANGE NOTICE (PCN)

#### **ATTACHMENT I - PCN # : A1508-03**

**PCN Type:** Manufacturing Site - Alternate Assembly Location

**Data Sheet Change:** None

No change in moisture sensitivity level (MSL)

#### **Detail Of Change:**

This notification is to advise our customers that IDT is adding ASECL, Taiwan as the alternate Assembly facility.

The material set details of the current and alternate assembly location is as shown in Table 1. The die attach and mold compound used at the alternate assembly are qualified IDT materials. There is no change from the existing qualified lead frame material and lead finish for the alternate assembly location.

There is no change to the moisture performance.

Table 1: Assembly Material Sets for The Existing and Alternate Assembly Location

	Existing Assembly (Amkor, Korea)	Alternate Assembly (ASECL, Taiwan)
Die Attach	CRM1085A	EN4900G
Wire	Au wire	PdCu wire
Mold Compound	G631BQF	G700LA

## PRODUCT/PROCESS CHANGE NOTICE (PCN)

#### **ATTACHMENT I - PCN # : A1508-03**

#### **Qualification Information and Qualification Data:**

**Affected Packages:** VFQFPN-36

**Assembly Material:** The affected package type is using ASECL standard materials shown on page 2

of this attachment.

**Qual Plan & Results:** Tests are in accordance with JEDEC47 recommended tests.

**Qualification Vehicle:** VFQFPN-32 ( 3 lots ) with material sets as shown in page 2

		Test R	esults (S	S / Rej)
Test Description	Test Method	Lot 1	Lot 2	Lot 3
* HAST - biased (130 °C/85% RH, 96 Hrs)	JESD22-A110	25/0	25/0	25/0
* Temperature Cycle / Condition B (-55 °C to +125 °C, 700 Cyc)	JESD22-A104	25/0	25/0	25/0
High Temp. Storage Test (150 °C, 1000 Hrs)	JESD22-A103	25/0	25/0	25/0

#### Note:

<sup>\*</sup> Test requires moisture pre-conditioning sequence per JESD22-A113 prior to stress test

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# PRODUCT/PROCESS CHANGE NOTICE (PCN)

### ATTACHMENT II - PCN #: A1508-03

#### **Affected Part Numbers**

Part Number	Part Number	Part Number	Part Number
F1300NBGI	F1358NBGI	F1320NBGI8	F1375NBGI8
F1375NBGI	F1325NBGI8	F1320NBGI	
F1358NBGI8	F1325NBGI	F1300NBGI8	

Pkg	Pkg and Si Attribute Pkg type Pkg x & y (mm) Pkg z (mm) Max Voltage	Amkor Korea NBG36 6.0 mm x 6.0 mm	ASECL Taiwan NBG36
Pkg	Pkg type Pkg x & y (mm) Pkg z (mm)		NBG36
Pkg	Pkg x & y (mm) Pkg z (mm)		
P KG	Pkg z (mm)		same
N		0.8 mm	same
	viax voltage	NA	NA
	Capacitors	NA	NA
S	Si Process	No change	No change same wafer
V	Vafer Size	No change	No change same wafer
	Die size (mm2)	No change	No change same wafer
	Die Aspect Ratio	No change	No change same wafer
	Die thickness (mils)	No change	No change same wafer
	Polyimide (Y/N)	No change	No change same wafer
	Silicon Metal Layers	No change	No change same wafer
	Scribe Width (um)	No change	No change same wafer
<u> </u>	JBM source	No change	No change same wafer
oot S	Silicon UBM Stack-up	No change	No change same wafer
Silicon & FL	Bump source	No change	No change same wafer
<u>ii</u> B	Bump pitch	No obongo	No change same wafer
iii I/	O & Core (um)	No change	No change same water
Т	Total Bump count	No change	No change same wafer
	Bump Diameter	No change	No change same wafer
	Bump Height	No change	No change same wafer
	Bump Metallurgy	No change	No change same wafer
V	Nafer Bump Flux	No change	No change same wafer
	CAM Flux	No change	No change same wafer
	Jnderfill Material	No change	No change same wafer
	Silicon UBM/SRO	No change	No change same wafer
	Halogen Free ?	NA	NA
S	Substrate Layers	NA	NA
	Substrate thickness	NA	NA
	Core thickness (um)	NA	NA
	Core Material	NA	NA
	Outer layer Lines/space um)	NA	NA
	Bump Pre-solder (SOP)	NA	NA
	Sump presolder (SOP)		
	neight/diameter	NA	NA
В	Bump Capture Pad/SRO IO	NA	NA
<u>o</u> (t	um)	101	10/1
	Substrate Ball Capture Pad/SRO (um)	NA	NA
] <u>[</u>	Number of PTH/M1-M2	NA	NA
	uVias Core PTH/Capture pad	NA	NA.
	um)	NA	NA
В	Substrate Design Rule & BOM	NA	NA
	Substrate Supplier	NA	NA
	Build up layer (thickness)	NA	NA
	Solder mask (thickness)	NA	NA
	C1 & C4 thickness (plate)	NA	NA
	C2 & C3 thickness (foil + blate)	NA	NA
	Surface finish (thickness)	NA	NA
	2nd level Ball count	NA	NA
2	2nd level BA Flux	NA	NA
	2nd Ball Dia (mm)	NA	NA
2	2nd level metallurgy	NA	NA
	2nd level ball pitch (mm)	NA	NA
2	2nd level metallurgy	NA	NA